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CLAIMS

1. A prodess for producing a ceramic film on a substrate, said process comprising:

preparing a film-forming fluid comprising a ceramic precursor, a catalyst, a surfactant and solvent(s);

depositing said film-forming fluid on said substrate; and

removing said solvent(s) from said film-forming fluid on said substrate to produce said ceramic film on said substrate.

wherein said ceramic film has a dielectric constant below 2.3, and a metal content of less than 500 ppm.

- 2. The method of claim 1, wherein said dielectric constant is from 2.2 to 1.3.
- 3. The method of claim 1, wherein said halide content is less than 1 ppm.
- 4. The method of claim 3, wherein said halide content is less than 500 ppb and said metal content is less than 1 ppm.
 - 5. The method of claim 1, wherein said metal content is less than 1 ppm.
 - 6. The method of claim 1, wherein said metal content is less than 100 ppb.
- 7. The method of claim 1, wherein said ceramic precursor is selected from the group consisting of tetra ethoxysilane, tetramethoxysilane, titanium (IV) isopropoxide, titanium (IV) methoxide and aluminum sec-butoxide.
- 8. The method of claim 1, wherein said catalyst is an organic acid and said film-forming fluid is free of mineral acid catalysts.
- 9. The method of claim 1, wherein said catalyst is selected from the group consisting of acetic acid, formic acid, glycolic acid, glycoylic acid and oxalic acid.
- 10. The method of claim 1, wherein said surfactant is nonionic and said film25 forming fluid is free of ionic surfactants.

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- 11. The method of claim 1, wherein said surfactant is a block copolymer of ethylene oxide and propylene oxide
- 12. The method of claim 1, wherein said surfactant is selected from the group consisting of block copolymers of ethylene oxide and propylene oxide and polyoxyethylene alkyl ethers.
- 13. The method of daim 1, wherein said surfactant is an ethoxylated acetylenic diol.
- 14. The method of claim 1, wherein said solvent is selected from the group consisting of methanol, isopropanol, isobutanol, ethanol and n-butanol.
- 15. The method of claim 1, wherein said solvent removing comprises spinning said substrate and calcining said ceramic film on said substrate.
- 16. The method of claim 1, wherein said film-forming fluid is a sol having a gelation time of at least 300 hours.
- 17. The method of claim 1, wherein said ceramic film has a porosity of about 50% to about 85%.
 - 18. A ceramic film produced by the process of claim 1.
- 19. The ceramic film of claim 18, wherein said dielectric constant is from 2.2 to 1.3.
- 20. The ceramic film of claim 18, wherein said halide content is less than 20 500 ppb.
 - 21. The ceramic film of claim 18, wherein said metal content is less than 1 ppm.
 - 22. The ceramic film of claim 18, wherein said metal content is less than 100 ppb.

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- 23. The ceramic film of claim 18, having a porosity of about 50% to about 80%.
- 24. The ceramic film of claim 18, having a porosity of about 55% to about 75%.
- 25. The ceramic film of claim 18, wherein said film includes pores sufficiently ordered in a plane of the substrate that an X-ray diffraction pattern of said film shows a Bragg diffraction at a d spacing greater than about 44 Å.
- 26. The ceramic film of claim 18, wherein said film does not include pores sufficiently ordered in a plane of the substrate such that an X-ray diffraction pattern of said film shows a Bragg diffraction.

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